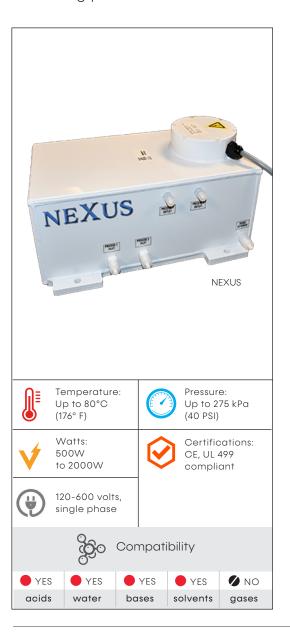




MULTI-LOOP CHEMICAL HEATER

Engineered for your process - manage multiple chambers with one heater! Building off of the popular SHC product line, the Nexus incorporates the same safe indirect heating technology to heat multiple process loops. Using a single heat source, the Nexus improves chamber-temperature matching performance for advanced processing requirements.



FEATURES

Reduced complexity

One set of controls for up to four process chambers.

Small space requirements.

Designed for performance

Allows for precise and stable temperature control for multiple chambers.

Low watt density design for lower surface temperatures.

Engineered for Safety

Heats chemicals and flammable solvents through indirect contact.

Patented purged housing for leak detection.

Advanced Cleanliness

O-ring free and crevice free design eliminates source for contamination.

All PFA wetted surfaces for acids and solvents.

APPLICATIONS

Semiconductor wafer cleaning

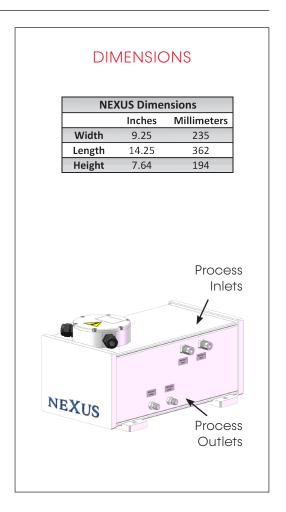


Nexus Multi-Loop Chemical/Solvent Heater

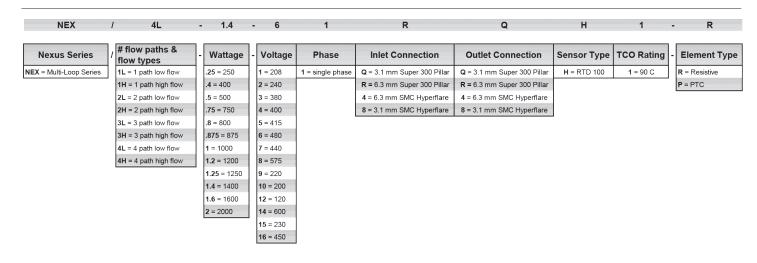
SPECIFICATIONS Wattages 500 kW to 1400 kW 120 volts to 480 volts, Voltages single phase Up to 80°C (176° F) Temperature Range Pressure Range Up to 275 kPa (40 PSI) Fluid Connections Inlets: Low Flow: 6.3mm (1/4") SP300 Nippon Pillar High Flow: 6.3mm (1/4") SMC Hyperflare Outlets: Low Flow: 3.1mm(1/8") SP300 Nippon Pillar High Flow: 3.1mm (1/8") SMC Hyperflare

RTD core sensors

Bi-mettalic over-temp sensor



MODEL NUMBER BREAKDOWN



Safety Features